

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of)
Yoshiaki HASEGAWA et al.)
Japanese Priority Application No. 2000-360615) Attn: Applications
Japanese Priority Date: November 28, 2000) Branch
For: METHOD FOR MANUFACTURING)
SEMICONDUCTOR AND METHOD FOR)
MANUFACTURING SEMICONDUCTOR)
DEVICE) Date: November 26, 2001

[Signature]
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7-15-02
JCE21 U.S. PTO
09/993771
11/27/01

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents and Trademarks
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application.

Copies of these references are submitted herewith in accordance with 37 C.F.R. 1.98(a).

Respectfully submitted,

[Signature]
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